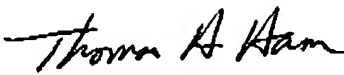
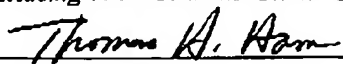


MAY 19 2006

<b>AMENDMENT TRANSMITTAL LETTER</b> Under Small Entity Status				Attorney Docket No: INK-002		
Application Serial Number: 10/829,593		Filing Date: 04/21/2004		Examiner: Rachuba, Maurina T.		Group Art Unit: 3723
Invention: APPARATUS AND METHOD FOR POLISHING SEMICONDUCTOR WAFERS USING ONE OR MORE POLISHING SURFACES						
TO THE COMMISSIONER OF PATENTS AND TRADEMARKS: Transmitted herewith is an amendment in the above-identified application. The fee has been calculated as shown below.						
<b>CLAIMS AS AMENDED</b>						
	CLAIMS REMAINING AFTER AMENDMENT		HIGHEST NUMBER PREVIOUSLY PAID FOR	NO. OF EXTRA CLAIMS PRESENT	RATE	ADDITIONAL FEE
TOTAL CLAIMS	113	MINUS	113	0	\$25	\$ 0.00
INDEP. CLAIMS	11	MINUS	11	0	\$100	\$ 0.00
_____ Petition is hereby made under 37 CFR 1.136(a) to extend the time for response to the Office Action _____ to and through _____, comprising an extension of the shortened statutory period of:  _____ one month (\$60)                      _____ three months (\$510) _____ two months (\$225)                      _____ four months (\$795)						
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT						\$ 0.00
_____ Small entity status of this application under 37 CFR 1.9 and 1.27 has been established by a verified statement previously submitted.  _____ A verified statement to establish small entity status under 37 CFR 1.9 and 1.27 is enclosed.  _____ A check in the amount of \$ _____ is attached.  _____ Charge \$ _____ to Deposit Account _____.  <u>  X  </u> No additional fee is required.						
<u>May 19, 2006</u> Date		 Thomas H. Ham Reg. No. 43,654				
CERTIFICATE OF TRANSMISSION UNDER 37 C.F.R. 1.8 I hereby certify that this paper (along with any paper referred to as being attached or enclosed) is being facsimile transmitted to the Patent and Trademark Office facsimile number (571) 273-8300 on May 19, 2006. Number of Pages: <u>5</u> (including TRANSMITTAL LETTER)   Thomas H. Ham						

Attorney Docket No. INK-002

PATENT APPLICATION

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## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): In Kwon Jeong

Group Art Unit: 3723

Serial No. 10/829,593

Confirmation No. 6718

Filed: April 21, 2004

Examiner: Rachuba, Maurina T.

For: APPARATUS AND METHOD FOR POLISHING SEMICONDUCTOR  
WAFERS USING ONE OR MORE POLISHING SURFACESMail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450RESPONSE TO FINAL OFFICE ACTION

Sir/Madam:

In response to the Final Office Action mailed on March 31, 2006, please consider the following **Remarks**, which begin on page 2 of this paper.

## CERTIFICATE OF TRANSMISSION UNDER 37 C.F.R. 1.8

I hereby certify that this paper (along with any paper referred to as being attached or enclosed) is being facsimile transmitted to the Patent and Trademark Office facsimile number (571) 273-8300 on May 19, 2006.

Number of Pages: 5 (including TRANSMITTAL LETTER)

Signed: Thomas H. Ham

Typed Name: Thomas H. Ham